

1. Record Nr.	UNISA996391565903316
Autore	Mede Joseph <1586-1638.>
Titolo	Diatribæ [[electronic resource]] : Discourses on divers texts of Scripture: delivered upon severall occasions, by Joseph Mede, B.D. late fellow of Christs Colledge in Cambridge. Printed by the authors own copy. The contents you shall finde in the next leafe
Pubbl/distr/stampa	London, : Printed by M.F. for John Clark, and are to be sold at his shop under S. Peters Church in Cornhill, M DC XLII. [1642]
Descrizione fisica	[8], 335, [1] p
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Part 1 only. A variant is bound with reissues of "Churches, that is, appropriate places of Christian worship" and "The reverence of Gods house" (STC 17765, 17769). Reproduction of the original in the British Library.
Sommario/riassunto	eebo-0018

2. Record Nr.	UNISA996216860303316
Autore	El-Sabh Mohammed I
Titolo	Oceanography of a Large-Scale Estuarine System The St. Lawrence
Pubbl/distr/stampa	[Place of publication not identified], : Springer New York, 1990
ISBN	1-118-66378-0
Descrizione fisica	1 online resource (444 pages)
Collana	Coastal and Estuarine Studies ; ; v.39
Disciplina	551.46/144
Soggetti	Biology Health & Biological Sciences Biology - General
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Bibliographic Level Mode of Issuance: Monograph

3. Record Nr.	UNINA9910139619603321
Titolo	Digital holography for MEMS and microsystem metrology // edited by Anand Asundi
Pubbl/distr/stampa	Chichester, England : , : Wiley, , 2011 ©2011
ISBN	1-283-17798-6 9786613177988 1-119-97278-7 1-119-99729-1 1-119-99730-5
Descrizione fisica	1 online resource (229 p.)
Collana	The Wiley microsystem and nanotechnology series
Disciplina	620.1127 621.381
Soggetti	Microelectromechanical systems - Measurement Microelectronics - Measurement Holographic testing Image processing - Digital techniques
Lingua di pubblicazione	Inglese
Formato	Materiale a stampa
Livello bibliografico	Monografia
Note generali	Description based upon print version of record.
Nota di bibliografia	Includes bibliographical references at the end of each chapters and index.
Nota di contenuto	Digital Holography for MEMS and Microsystem Metrology; Contents; About the Editor; Contributors; Series Preface; Acknowledgements; Abbreviations; 1 Introduction; 2 Digital Reflection Holography and Applications; 2.1 Introduction to Digital Holography and Methods; 2.1.1 Holography and Digital Holography; 2.1.2 Digital Recording Mechanism; 2.1.3 Numerical Reconstruction Methods; 2.2 Reflection Digital Holographic Microscope (DHM) Systems Development; 2.2.1 Optical Systems and Methodology; 2.3 3D Imaging, Static and Dynamic Measurements; 2.3.1 Numerical Phase and 3D Measurements 2.3.2 Digital Holographic Interferometry2.4 MEMS/Microsystems Characterization Applications; 2.4.1 3D Measurements; 2.4.2 Static Measurements and Dynamic Interferometric Measurement; 2.4.3 Vibration Analysis; References; 3 Digital Transmission Holography and

Applications; 3.1 Historical Introduction; 3.2 The Foundation of Digital Holography [30]; 3.2.1 Theoretical Analysis of Wavefront Interference; 3.2.2 Digital Hologram Recording and Reconstruction; 3.2.3 Different Numerical Reconstruction Algorithms; 3.3 Digital Holographic Microscopy System
 3.3.1 Digital Holographic Microscopy with Physical Spherical Phase Compensation
 3.3.2 Lens-Less Common-Path Digital Holographic Microscope; 3.3.3 Common-Path Digital Holographic Microscope; 3.3.4 Digital Holographic Microscopy with Quasi-Physical Spherical Phase Compensation : Light with Long Coherence Length; 3.3.5 Digital Holographic Microscopy with Quasi-Physical Spherical Phase Compensation : Light with Short Coherence Length; 3.4 Conclusion; References; 4 Digital In-Line Holography and Applications; 4.1 Background; 4.2 Digital In-Line Holography; 4.2.1 Recording and Reconstruction
 4.3 Methodology for 2D Measurement of Micro-Particles
 4.3.1 Numerical Reconstruction, Pre-Processing and Background Correction; 4.3.2 Image Segmentation; 4.3.3 Particle Focusing; 4.3.4 Particle Size Measurement; 4.4 Validation and Performance of the 2D Measurement Method; 4.4.1 Verification of the Focusing Algorithm; 4.4.2 Spherical Beads on a Glass Slide; 4.4.3 Microspheres in a Flowing System Normalized Population; 4.4.4 10 m Microspheres Suspension; 4.4.5 Measurement of Microfibers; 4.5 Methodology for 3D Measurement of Micro-Fibers; 4.5.1 Method 1: The 3D Point Cloud Method
 4.5.2 Method 2: The Superimposition Method
 4.6 Validation and Performance of the 3D Measurement Methods; 4.6.1 Experiment with a Single Fiber; 4.6.2 3D Measurements of Micro-Fibers in Suspension; 4.7 Conclusion; References; 5 Other Applications; 5.1 Recording Plane Division Multiplexing (RDM) in Digital Holography for Resolution Enhancement; 5.1.1 Introduction of the Recording Plane Division Multiplexing Technique; 5.1.1.1 The SM Technique; 5.1.1.2 The ADM Technique; 5.1.1.3 The WDM Technique; 5.1.1.4 The PM Technique; 5.1.2 RDM Implemented in Pulsed Digital Holography for Ultra-Fast Recording
 5.1.2.1 Introduction

Sommario/riassunto

Approaching the topic of digital holography from the practical perspective of industrial inspection, Digital Holography for MEMS and Microsystem Metrology describes the process of digital holography and its growing applications for MEMS characterization, residual stress measurement, design and evaluation, and device testing and inspection. Asundi also provides a thorough theoretical grounding that enables the reader to understand basic concepts and thus identify areas where this technique can be adopted. This combination of both practical and theoretical approach will ensure the